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PATENT  
Attorney Docket No.: A7188/T47800  
Client Ref. No.: AMAT No.  
007188/DISPLAY/AKT/BG

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

Sheng Sun et al.

Application No.: 10/817,611

Filed: April 2, 2004

For: METHOD AND SYSTEM FOR  
CONTROL OF PROCESSING  
CONDITIONS IN PLASMA  
PROCESSING SYSTEMS

Customer No.: 57385

Confirmation No. 2449

Examiner: Joel G. Horning

Technology Center/Art Unit: 1792

**AMENDMENT**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Commissioner:

In response to the final Office Action mailed November 4, 2009, please enter the  
following amendments and remarks:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this  
paper.

**Remarks** begin on page 7 of this paper.